Hans Oechsner

Hans Oechsner got his university education in Physics, Mathematics and Chemistry at the University of Würzburg, where he earned his Diploma degree in Physics in 1960 and his Doctor's degree (Dr.rer.nat) in 1963. After a research period at the Eidgenössische Technische Hochschule (ETH) in Zürich/Switzerland in 1968 he returned to Würzburg for his Habilitation in Experimental Physics. 1972 he became Professor of Physics at the Technical University Clausthal and moved 1981 to the Technical University of Kaiserslautern as Ordinary Professor and Chair of Technical Physics from which he retired in 2000. At this university he founded in 1989 the Institute for Surface and Thin Film Analysis IFOS. He was Director of this institute until 2002 and works there till today as a Scientific Consultant.

As major awards he received the Technology Transfer Prize of the Federal Republic of Germany and the Luxemburg-Prize for Scientific Cooperation between Luxemburg and Germany. Hans Oechsner served from 1997 to 2002 as President of the German Vacuum Society and is honorary member of the Analytical Division of the German Chemical Society and of the German Vacuum Society. He authored or co-authored about 290 scientific papers and book chapters, was editing author of a book on "Thin Film and Depth Profile Analysis", and edited a number of international conference proceedings. He held and holds 7 international patents.

Originally engaged in low pressure plasma physics, he moved early to surface and thin film physics. His main interests were in ion surface interaction , but also in chemical processes at surfaces, in thin films and at interfaces. Based on his background in plasma physics, ion beam and plasma assisted techniques for surface and thin film technology, including the development of new ion and plasma beam sources, became then an essential part of his work. Chemical and structural surface , thin film and depth profile analysis is his second major field which led to the foundation of the IFOS. Hans Oechsner got international recognition by the development of Secondary Neutral Mass Spectrometry SNMS, but also by adding other techniques as Work Function Microscopy WFS to the arsenal of instrumental analysis.